Quality of silicon substrate and point defects (6) IR absorption of CO, NN, NO ring Osaka Pref. Univ.<sup>1</sup> <sup>o</sup>N. Inoue<sup>1</sup>, S. Kawamata<sup>1</sup> and S. Okuda<sup>1</sup> シリコン結晶基板の品質と点欠陥 (6) CO, NN, NO ringの赤外吸収 大阪府立大研究推進<sup>1</sup> <sup>o</sup>井上直久<sup>1</sup>, 川又修一<sup>1</sup>, 奥田修一<sup>1</sup>, E-mail: inouen@riast.osakafu-u.ac.jp

Silicon device has become the brain (=IC chip, from 1995/ cell in the neural network) and the heart (=power device, from 2005/ blood in the vascular network) of the world. Nitrogen doping in silicon is widely used to suppress both vacancy (V) and interstitial (I) type grown-in microdefects in the substrate for IC chip [1]. Dominant state of N was established to be Si-N-Si-N 4-atom <u>NN ring [2]</u>. Carbon is used to control lifetime of power device. Its configuration was found before to be <u>CO ring [3]</u>. Therefore, the human life is constructed on this ring. In addition, shallow thermal donor (STD) and O dimer (working for the precipitation, thermal donor formation and O fast diffusion) are composed of <u>NO</u> [4] and sometimes of <u>OO</u> ring [5], respectively. Therefore, it is necessary to understand them well. All of them show IR absorption by the local vibration modes (LVM) directly originating from individual atom (for example STD/NO and NOO is shown in the figure). Collaboration

with theoretical work is an advantage of IR experiment. This made it possible to find, identify, measure, analyze kinetics and reveal the role in device of them by IR as summarized in the Table.

We found and identified IR absorptions from NO+O<sub>0.2</sub> STD (figure) [6] which showed good agreement with the calculation [7]. LVM of CO+O was established also [8].

In addition to 4atom ring, NN, NO [9] and OO [10] has a **common "chain structure"** which helps understanding of both complexes also. For these works we began constructing IR database [11] and open in a website now.



Table IR absorption of various 4 member rings, observation and calculation

Complex	Experiment		Calculation	
	LVM, cm <sup>-1</sup> ,	Author, year, paper	LVM, cm <sup>-1</sup> ,	Author, year, paper
СО	526,550,586,742,865,	Newman71RadEff	1154	C.Kaneta90ICPS
	1115		559,565,604,625,925,1141	Jones92PRL
СО+О	1020	Londos20Cryst		Potsidi20Cryst.
NN	766, 963	Abe81MRS	688.6, 918.7	Jones94PRL
			840, 1022	Inoue02ECS
NN+ <u>O</u>	801,996, <u>1027</u>	Wagner88APhysA	671,724,808 <u>,861</u> ,1070	Jones94SST
			847,1024	Inoue02ECS
NN+20	810, 1018	Wagner88APhysA	1022	Inoue02ECS
				Fujita06ECS
NO	714 <mark>,</mark>	Inoue18ECS	794, 915	Inoue06MSEB
			722, 801, 1001	Fujita07PhysB
NO+ <u>O</u>	736* <mark>,</mark>	Inoue18ECS	838,915 <u>,1025</u>	Inoue06MSEB
			<u>670</u> ,794,812 <u>,977</u> ,1022	Fujita07PhysB
NO+2O	973, 1002	Inoue05SSP,06MSEB		
ONO(+O)	855	Inoue05SSP	673,720,858,894,1051	Ewels96PRL
			658,751,856,970,1084,	Fujita07PhysB
	(860, 1070LT)	Alt09JAP		

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